

OF APPLICATION

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

ATTN: OFFICE OF PUBLICATIONS

Notice of Allowance Mailed 01/11/2005 - Batch/Confirmation No.

D. Vu

6923

Takamitsu HIGUCHI et al.

In re the Application of

Group Art Unit: 2818

Application No.:

10/644,989 Examiner:

Filed: August 21, 2003

Docket No.: 116916

For:

SUBSTRATE FOR ELECTRONIC DEVICES, MANUFACTURING METHOD

THEREOF, AND ELECTRONIC DEVICE

## INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- 1. This Information Disclosure Statement is being filed more than three months after the U.S. filing date and after the mailing date of a Final Rejection, Notice of Allowance, or other action that closes prosecution (e.g., Quayle Action), but before payment of the Issue Fee. Attached is our Check No. 163573 in the amount of \$180.00 in payment of the fee under 37 CFR §1.17(p). Please credit or debit Deposit Account No. 15-0461 as needed to ensure consideration of the disclosed information. Two duplicate copies of this paper are attached.
  - a. I hereby certify that each item of information contained in this Information Disclosure Statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Information Disclosure Statement.

    37 CFR §1.97(e)(1).
- 2. The references were cited in a counterpart foreign application. An English language version of the European search report is attached for the Examiner's information.

3. U.S. 5,270,298 and Haakenaasen reference (which were cited in the foreign search report, but are not attached) were submitted to the Patent Office on August 21,

2003 as reference no. 4 and reference no. 29, respectively.

Respectfully submitted,

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JAO:JWF/ldg

Date: February 11, 2005

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Sheet 1 of 1

Form PTO-1449 (REV. 8-83)	)	US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY D	ATTY DOCKET NO. 116916		APPLICATION NO. 10/644,989		
INFORMATION DISCLOSURE STATEMENT								
(Use several sheets if necessary)			APPLICANT(S) Takamitsu HIGUCHI et al.					
			FILING DATE August 21, 2003		GRO1 2818	GROUP 2818		
		U.S. PA	TENT DOCU	JMENTS	<u></u>			
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)								
	A	Pignolet A., et al., "Large Area Pulsed Laser Deposition of Aurivillus-type Layered Perovskite Thin Films", Ferrorelectrics, Overseas Publishers Associations, Amsterdam, NL, , Vol. 202, No. 1-4, 1997, pp. 285-298.						
•	В	Mechin L. et al., "A combined x-ray specular reflectivity and spectroscopic ellipsometry study of CeO <sub>2</sub> /yttria-stabilized-zirconia bilayers on Si(100) substrates", Journal of Applied Physics, American Institute of Physics, New York, US, Vol. 84, No. 9, 1 November 1998, pp. 4935-4940.						
	С	Matthee T., et al., "Orientation relationships of epitaxial oxide buffer layers on silicon (100) for high-temperature superconducting Yba2Cu307-x films", Applied Physics Letters USA, Vol. 61, No. 10, 7 September 1992, pp. 1240-1242.						
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EXAMINER				DA	DATE CONSIDERED			
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

Date: February 11, 2005